CLAIMS

1. A physical vapor deposition (PVD) chamber, comprising a chamber body, an upper electrode assembly being arranged in the chamber body, and the upper electrode assembly including a base plate assembly configured to carry a magnetron, a backplate superimposed~~arranged~~ at an interval with the base plate assembly, and a connection assembly for connecting the base plate assembly to the backplate, the backplate being arranged at a side of the base plate assembly away from the magnetron;

wherein, the connection assembly includes a connection bolt, a bolt head of the connection bolt is connected to the base plate assembly, and a bolt of the connection bolt is threadedly connected to the backplate~~the connection assembly is threadedly connected to the backplate, so that the interval between the base plate assembly and the backplate is able to be adjusted by moving the connection assembly relative to the backplate~~.

2. The PVD chamber according to claim 1, wherein a plurality of connection assemblies are included, and the plurality of connection assemblies are staggered with the magnetron and are arranged at intervals~~the connection assembly includes a connection bolt, and the connection bolt includes a bolt head and a bolt, wherein the bolt head is connected to the base plate assembly, and the bolt is threadedly connected to the backplate~~.

3. The PVD chamber according to claim 2, wherein the bolt head of the connection bolt is rotatably connected to the base plate assembly.

4. The PVD chamber according to claim 3, wherein:

the bolt head of the connection bolt is configured to have a convex spherical surface; and

a spherical seat cooperating with the convex spherical surface is provided on the base plate assembly.

~~the base plate assembly includes a base plate body, a first groove with a first concave spherical surface being arranged in the base plate body, the bolt head being arranged in the first groove, and the convex spherical surface cooperating with to the first concave spherical surface.~~

5. The PVD chamber according to claim 4, wherein:

~~an opening end of the first groove is located on a first surface of the base plate body opposite to the backplate, and the bolt is located outside of the base plate body and is threadedly connected to the backplate; or~~

~~the opening end of the first groove is located inside the base plate body, a through-hole is provided in the base plate body, one end of the through-hole is communicated with the opening end of the first groove, the other end is located on the first surface, a diameter of the through-hole is smaller than a diameter of the convex spherical surface, and the bolt extends from the through-hole and is threadedly connected to the backplate~~the base plate assembly includes a base plate body, the base plate body is provided with the spherical seat and a through hole communicated with the spherical seat, the convex spherical surface of the connection bolt fits in the spherical seat, and the bolt extends from the through hole, a diameter of the convex spherical surface being greater than a diameter of the through hole.

6. The PVD chamber according to claim 5, wherein the base plate assembly further includes a fixing module having a concave spherical surface cooperating with the convex

spherical surface, the fixing module is fixed on the base plate body, and the concave spherical surface fits with the convex spherical surface~~, the fixing module being detachably connected to the base plate body, the fixing module being provided with a second groove with a second concave spherical surface, the second concave spherical surface being aligned with the first concave spherical surface to form a continuous concave spherical surface, the bolt head being fixed between the first groove and the second groove, and the convex spherical surface cooperating with the first concave spherical surface and the second concave spherical surface~~.

7. The PVD chamber according to claim 6, wherein a recess is formed at the base plate body, the spherical seat is formed on a bottom surface of the recess, the fixing module is embedded in the recess, and a surface of the fixing module ~~that is exposed to the base plate body~~ is flush with a ~~second~~ surface of the base plate body ~~facing away from the first surface~~.

8. The PVD chamber according to claim 6 or 7, wherein an operation hole leading to the convex spherical surface is provided at the fixing module, ~~one end of the operation hole is communicated with the second groove, the other end is located on the surface of the fixing module that is exposed to the base plate body,~~ and an operation groove corresponding to the operation hole is provided at the convex spherical surface~~bolt head~~.

9. The PVD chamber according to ~~any one of~~ claim~~s 1 to~~ 8, wherein the fixing module is fixedly connected with the base plate body through a screw ~~a plurality of connection assemblies are included, the plurality of connection assemblies are arranged at intervals, and each connection assembly is mutually staggered with the magnetron~~.

10. A physical vapor deposition (PVD) apparatus, comprising the PVD chamber according to any one of claims 1 to 9.